

METHOD AND APPARATUS FOR APPLICATION  
OF A MATERIAL TO A SUBSTRATE

Abstract of the Disclosure

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An apparatus for applying a material to a substrate includes a housing having an inlet passage, a plurality of exit openings, and a recess in fluid communication between the inlet passage and the exit openings. A valve element is disposed in the recess wherein the valve element includes a first portion and a second portion axially displaced from the first portion. Means are provided for moving the valve element in the recess such that the first portion provides continuous fluid communication between the inlet passage and one of the exit openings during movement of the valve element and the second portion provides intermittent fluid communication between the inlet passage and another of the exit openings during movement of the valve element. A method of applying a material to a substrate is also disclosed.

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